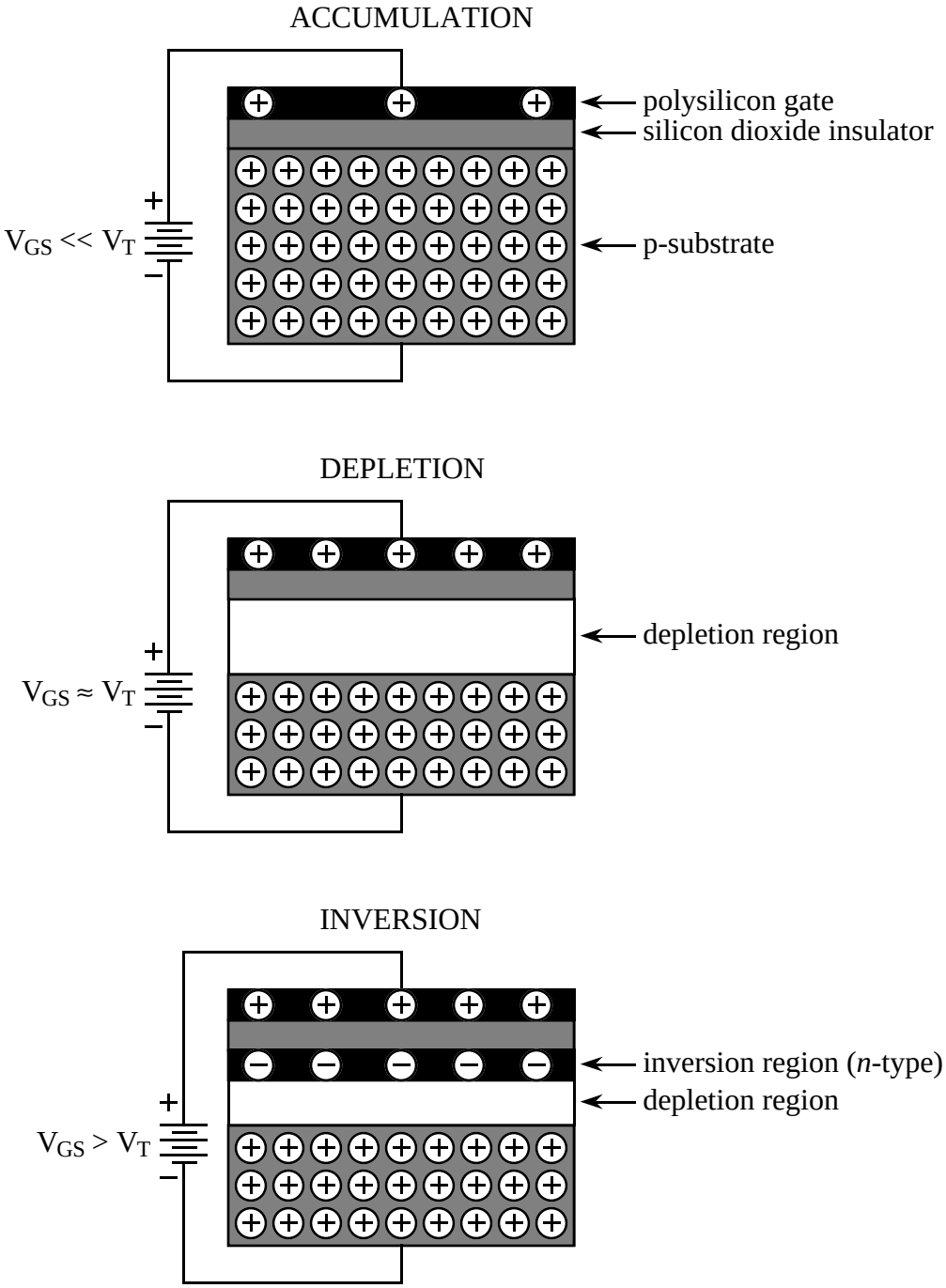
MOSFET Device Operation



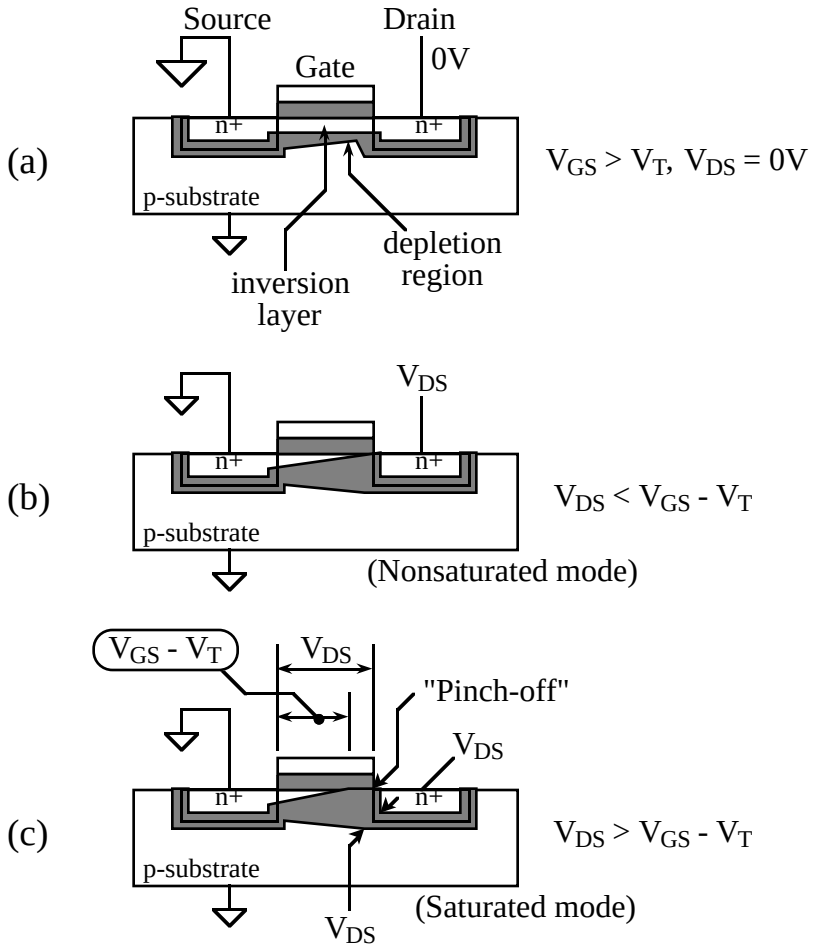
Enhancement-mode *n*MOS transistor cross-section

Holes are repelled from the gate by positive V_{GS} (*n*MOSFET)

At the onset of INVERSION, *electrons* attracted under the gate to form channel.

For a depletion-mode *n*MOS, area under gate is actually a lightly doped *n*-type material so that threshold voltage is < 0V.

MOSFET Structure versus Bias



Cross-section (a): potential in channel same everywhere because $V_{GS} = V_{GD}$, channel "depth" same everywhere since $V_{GS} > V_T$ and $V_{GD} > V_T$

Cross-section (b): Depth of channel varies somewhat linearly with V_{GS} *and* V_{DS}. As V_{DS} is increased, the drain-side of channel (just beneath the gate) becomes "pinched" because V_{GD} becomes less and less.

Cross-section (c): Here the current depends only on V_{GS} and not V_{DS} (if we neglect channel-length modulation) and the channel becomes completely pinched-off near the drain. With $V_{DS} > V_{GS} - V_T$ but $V_S = 0V$, then $V_D > V_G - V_T$ and hence, $V_T > V_{GD}$, i.e., $V_{gate\text{-}to\text{-}drain}$ is less than the threshold voltage.

How does conduction occur *after* "pinch-off"? Electrons enter channel from source, then are swept across depletion region near drain by the positive drain voltage with respect to source (V_{DS}).

MOSFET Threshold Voltage

$V_T = V_{T\text{-}MOS} + V_{fb}$ ($V_{T\text{-}MOS}$ is positive for *n*MOS, negative for *p*MOS)

$V_{T\text{-}MOS}$ — ideal threshold voltage for a MOS capacitor (the capacitor formed between the gate and substrate)

V_{fb} — Flatband voltage

$$V_{T\text{-}MOS} = 2\phi_b + \frac{Q_b}{C_{ox}}$$ (Note: "Q_b" sometimes referred to as "Q_{bo}")

$$\phi_b = \frac{kT}{q} \ln\left(\frac{N_A}{n_i}\right) \Leftarrow \text{bulk Fermi potential}$$

C_{ox} = oxide capacitance, inversely proportional to oxide thickness $\left(C_{ox} = \frac{\varepsilon_{ox}}{t_{ox}}\right)$

$$Q_b = \sqrt{2\varepsilon_{si} \cdot q \cdot N_A \cdot 2\phi_b}$$ $\Leftarrow$ bulk charge term (total charge stored in depletion layer), *p*-substrate in this case

Bulk potential — potential difference between Fermi level in intrinsic semiconductor and Fermi level in doped semiconductor

Fermi level is the average energy level in a material. For intrinsic materials, it is halfway between the valence band and conduction band.

p-type $\Rightarrow$ Fermi level closer to valence band
n-type $\Rightarrow$ Fermi level closer to conduction band

Other Constants (see text for values):
- k = Boltzmann's constant (eV/K, J/K)
- q = Electronic charge (coulombs)
- T = temperature ($^\circ$K)
- N_A = carrier density in doped semiconductor
- n_i = intrinsic carrier concentration in Silicon
- ε_{si} = permittivity of Silicon = $\varepsilon_r \cdot \varepsilon_o$
  - ε_r =11.7 (relative Silicon permittivity)
  - ε_o (permittivity of free space)

MOSFET Threshold Voltage (continued)

$V_{fb} = \Ø_{ms} - \frac{Q_{fc}}{C_{ox}}$ ($\Ø_{ms}$ = gate work function, Q_{fc} sometimes referred to as Q_{ss})

$Q_{fc} \Rightarrow$ fixed charge due to surface states which arise due to imperfections in silicon oxide interface and doping

$\Ø_{ms} \Rightarrow$ gate work function which is the work function difference between the gate material and substrate

$$\Ø_{ms} = -\left(\frac{E_g}{2q} + \Ø_b\right)$$

$E_g \Rightarrow$ Bandgap energy of Silicon (temperature dependent)

$\Ø_b \Rightarrow$ bulk Fermi potential

Note: E_g is actually in electron volts, $1eV = 1q \cdot 1V$, so "q" 's in $\Ø_{ms}$ expression cancel out.

Two common techniques for increasing the native threshold voltage of a MOS device:

(1) Vary the doping concentration at the silicon-insulator interface through ion implantation (in process step called "threshold adjustment")

$\Rightarrow$ affects Q_{fc} (Q_{ss}, surface state charge)

(2) Use different insulating material for gate

$\Rightarrow$ affects C_{ox}

Between transistors, use very thick oxide (>> t_{ox}) to increase threshold voltage so that substrate surface does not become inverted through normal circuit voltage (obviously you do not want signal wire voltages and V_{DD} lines inverting substrate). This keeps transistors electronically isolated from each other.

Example V_T calculation: Calculate the native threshold voltage for an *n*-transistor at 300°K for a process with a Si substrate with $N_A = 1.80 \times 10^{-16}cm^{-3}$, a SiO_2 gate oxide with thickness 200Å. (Assume $\emptyset_{ms}$ = -0.9V, Q_{fc} = 0C.)

$$\emptyset_b = 0.02586 \ln\frac{1.80 \times 10^{-16}}{1.45 \times 10^{10}} = 0.36V;$$

$$\text{note } \frac{kT}{q} = 0.02586V \text{ @ } T = 300^\circ K$$

with

$$C_{ox} = \frac{3.9 \times 8.85 \times 10^{-14}}{0.2 \times 10^{-5}} = 1.726 \times 10^{-7} \frac{\text{Farads}}{cm^2}$$

resulting in

$$V_T = \emptyset_{ms} + \frac{\sqrt{2\varepsilon_{si} q N_A 2\emptyset_b}}{C_{ox}} + 2\emptyset_b = (-0.9 + 0.384 + 0.72)V = 0.16V$$

This device has a *very* low threshold voltage.

Substrate (bulk) bias effect on Threshold Voltage

For *n*MOS, substrate usually tied to ground. However, if V_{SB} (source-to-bulk) ≠ 0V, the threshold equations become:

$$V_T = V_{fb} + 2\emptyset_b + \frac{\sqrt{2\varepsilon_{si} q N_A (2\emptyset_b + |V_{SB}|)}}{C_{ox}}$$

$$V_T = V_{TO} + \gamma\left(\sqrt{2\emptyset_b + |V_{SB}|} - \sqrt{2\emptyset_b}\right)$$

where V_{TO} is threshold voltage when V_{SB} = 0V and γ is a constant which describes substrate bias effect.

$$\gamma = \frac{t_{ox}}{\varepsilon_{ox}}\sqrt{2\varepsilon_{si} q N_A} = \frac{1}{C_{ox}}\sqrt{2\varepsilon_{si} q N_A}$$

Values of γ usually range from (0.4 to 1.2)$V^{1/2}$.

In SPICE, γ = GAMMA, V_{TO} = VTO, N_A = NSUB, $\emptyset_s = 2\emptyset_b$ is PHI.

Example of substrate bias effect on threshold voltage: With $N_A = 3\times10^{16}cm^{-3}$, t_{ox} = 200Å, $\varepsilon_{ox} = 3.9\times8.85\times10^{-14}$F/cm, $\varepsilon_{si} = 11.7\times8.85\times10^{-14}$F/cm, and q = 1.6×10^{-19}Coulomb

$$\gamma = \frac{0.2\times10^{-5}}{3.9\times8.85\times10^{-14}}\sqrt{2\times1.6\times10^{-19}\times11.7\times8.85\times10^{-14}\times3\times10^{16}} = 0.57V^{1/2}$$

$$\emptyset_b = 0.02586 \ln\frac{3\times10^{16}}{1.5\times10^{10}} = 0.375V$$

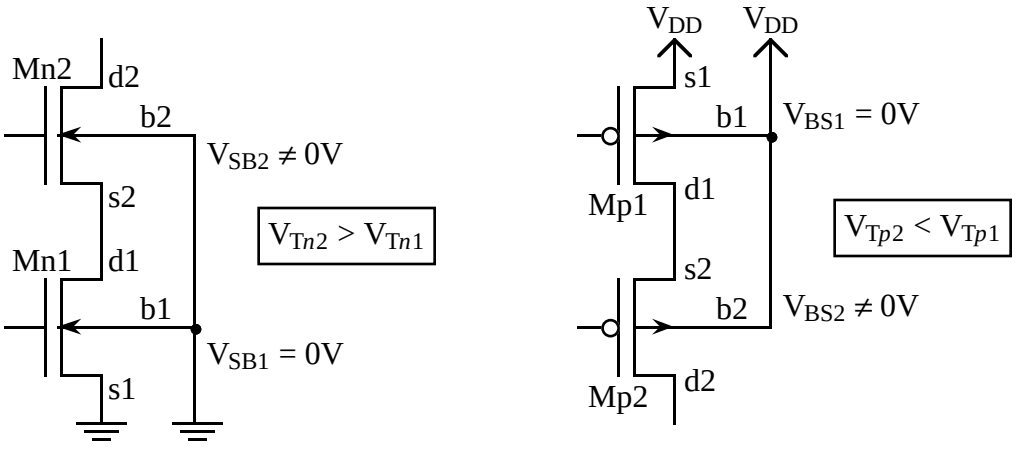
At a V_{SB} = 2.5V,

$$V_T = V_{TO} + 0.57\left(\sqrt{0.75 + 2.5} + \sqrt{0.75}\right)$$

$$V_T = V_{TO} + 0.53V$$

In analog designs it is quite common to use substrate bias to shift threshold voltage.

Note: When connecting devices in series, V_T of top device will increase if V_B tied to appropriate rail because V_{SB} is not zero.



Actual shift in threshold voltage due to the above arrangement is very small.

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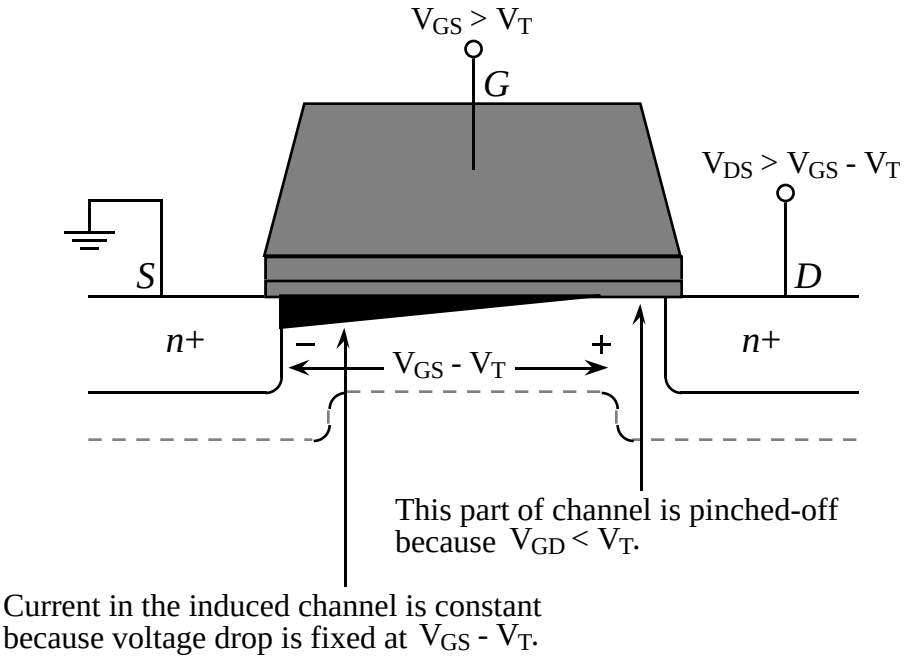
Revisit operation under Saturation



Ideal equation $I_D = \frac{ß_n}{2}(V_{GS} - V_{Tn})^2$ is not entirely accurate because pinch-off point under gate is influenced by V_{DS}. This influence of V_{DS} on pinch-off *essentially* modifies the length of the channel (channel length modulation effect).

New equation for Saturation

$$I_D = \frac{ß}{2}(V_{GS} - V_{Tn})^2(1 + \lambda V_{DS})$$

λ in SPICE is called LAMBDA, and is the channel length modulation factor. Empirical values range from (0.02 to 0.005) V^{-1}.

If we rewrite our current equation as

$$I_D = \frac{K'}{2}\frac{W}{L}(V_{GS} - V_{Tn})^2(1 + \lambda V_{DS})$$

then when $\lambda > 0V^{-1}$, the effective channel length is reduced. Be careful not to confuse channel length with gate length. In saturated pinch-off, they are *not* equal!